

Abstract of the Disclosure:

A measuring apparatus includes at least one microsensor having at least two chambers filled with a gas. The chambers are connected to one another by at least one channel. Moreover, 5 the chambers are sealed off to the outside in a gastight manner. Also provided is a detection device for detecting a gas stream flowing in the channel, which gas stream arises on account of different pressures prevailing in the chambers. The invention also relates to a method for producing the 10 microsensor according to the invention.

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